

# EUROPEAN PATENT OFFICE

## Patent Abstracts of Japan

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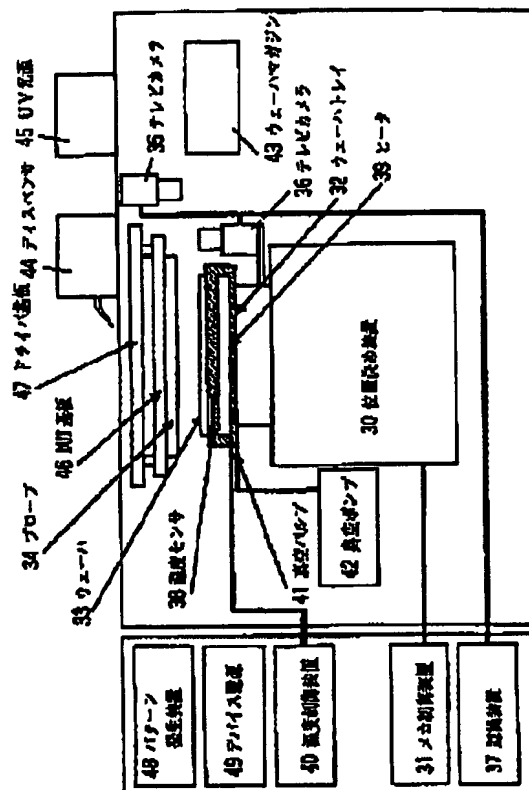
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TITLE : BURN-IN DEVICE



ABSTRACT : PROBLEM TO BE SOLVED: To continuously carry out a burn-in process by connecting a wafer and a probe together and then performing heating and signal application when a batch burn-in process is performed in a wafer state.

SOLUTION: While the wafer 33 as a DUT and the probe 34 are brought under heating control by a temperature sensor 38, a heater 39, and a temperature controller 40 after being connected together, a driver substrate 47 is connected to a DUT substrate 48 holding the probe 34, electric power is supplied to the wafer 33 from a device power source 49, and a signal is supplied from a pattern generating device 48, so that the burn-in process carried out in the wafer state.

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